



SFW 2881/1  
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Docket No.: H6808.0004/P004  
(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:  
Atsushi Takane et al.

Application No.: 10/082,286

Art Unit: 2881

Filed: February 26, 2002

Examiner: P. A. Johnston

For: SEMICONDUCTOR INSPECTION SYSTEM

**AMENDMENT**

MS Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

**INTRODUCTORY COMMENTS**

In response to the Office Action dated January 16, 2004 (Paper No. 20031229), please amend the above-identified U.S. patent application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks** begin on page 10 of this paper.